

## ESP PHOTOMEMORY CENTERS IN THE Si-SiO<sub>2</sub> STRUCTURE

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It is known that defects in semiconductor-dielectric structures can be responsible for long-term optical memory. Information on the nature of these centers can sometimes be obtained by the ESP method [1]. The present paper is concerned with an investigation of the Si-SiO<sub>2</sub> structure subjected to UV radiation.

The ESP spectra were recorded on an EPR-3 spectrometer with operating frequency of 10 GHz and sensitivity of not less than 10<sup>11</sup> spin/gauss. The studies were performed with Si (n type,  $\rho = 1000 \text{ ohm}\cdot\text{cm}$ ) monocrystals, vibration-pulverized under vacuum. The specimens were then oxidized in oxygen at  $T = 1000\text{-}1100^\circ\text{C}$  for 4 hr. Then the specimens were illuminated by a DKSSh-100 xenon lamp upon continuous rotation of a quartz ampule with a specimen. All the experiments were performed under a vacuum not poorer than 10<sup>-6</sup> mm Hg.

It was found that oxidation of Si results in the appearance of two ESP signals, I<sub>1</sub> and I<sub>2</sub> (Fig. 1), the parameters of which are close to the parameters of signal detected by Kropman, et al. [2]. Signals I<sub>1</sub> and I<sub>2</sub> were easily saturated at microwave powers of ~1 mW. Vacuum heating did not change the intensity of signal I<sub>1</sub>, while increasing somewhat the intensity of signal I<sub>2</sub> (Fig. 2a). Ultra-violet irradiation of the starting oxidized Si did not modify signals I<sub>1</sub> and I<sub>2</sub>, nor did it cause the generation of new signals. Unlike this, UF irradiation of specimens heated under vacuum was accompanied by a significant rise in signal I<sub>2</sub>, with the intensity as a function of the vacuuming temperature (Fig. 2b) (the intensity of signal I<sub>1</sub> did not change after UV irradiation). As is seen from Fig. 2c, vacuum heating of a preirradiated specimen reduces the level of signal I<sub>2</sub>. Multiple alternation of vacuum heating UV irradiation resulted in reversible changes of signal I<sub>2</sub>.

The parameters of signals I<sub>1</sub> and I<sub>2</sub> (the g factor, line width and the UHF power at which saturation occurs) are in satisfactory agreement with the corresponding characteristics of signals from E<sub>1</sub>' and E<sub>2</sub>' centers in quartz and germanium glasses subjected to high-energy irradiation [3, 4]. It can be presently regarded as established that oxygen vacancies are responsible for the E<sub>1</sub>' signal [5], whereas the E<sub>2</sub>' signal is preferably associated with the oxygen vacancy + oxygen complex in the interstice.

The region of localization of paramagnetic centers was determined by HF etching of previously irradiated specimens. It was found that intensity I<sub>2</sub> decreases 5-6 fold, whereas I<sub>1</sub> does not change much. Etching in a type CP agent

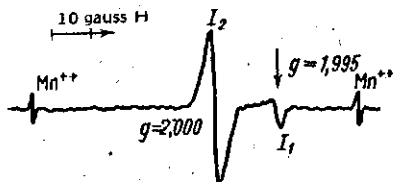


Fig. 1

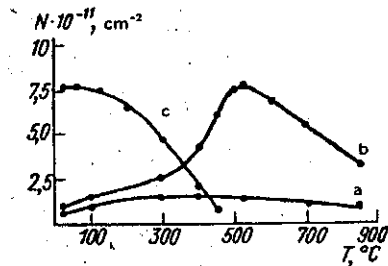


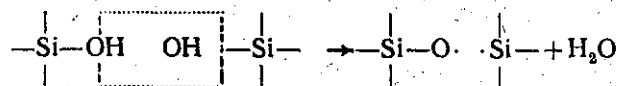
Fig. 2

Fig. 1. Typical ESP spectrum following the irradiation of an Si-SiO<sub>2</sub> structure.

Fig. 2. Concentration of paramagnetic centers I<sub>2</sub> vs vacuum-heating temperature: a) prior to UV irradiation; b) following UV irradiation; c) vacuum anneal of an UV irradiated specimen.

fully destroyed both signals. The qualitative conclusions that can be drawn from this are as follows. A significant part of centers I<sub>1</sub> is localized in the oxide layer (centers I<sub>2</sub><sup>0</sup>); this group of centers vanishes when SiO<sub>2</sub> is dissolved in HF. Virtually all the I<sub>1</sub> centers and a small part of I<sub>2</sub> (centers I<sub>2</sub><sup>intf</sup>) are situated in the immediate proximity of the Si-SiO<sub>2</sub> interface; this group of centers vanishes only after etching the silicon. The existence of oxygen vacancies (I<sub>1</sub> centers) and vacancy + oxygen complexes (I<sub>2</sub><sup>intf</sup> centers) in the transition Si-SiO<sub>2</sub> layer is in satisfactory agreement with a large volume of electron-microscopy data (among others the paper by Ishizaka, et al. [6]), according to whom the layer consists of SiO<sub>x</sub> groups, where x < 2. Ultraviolet irradiation does not modify I<sub>1</sub> or I<sub>2</sub><sup>intf</sup>. Apparently the energy location of these centers is such that in their initial state they are positively charged and paramagnetic.

The behavior of centers I<sub>2</sub><sup>0</sup> is different. Ultraviolet irradiation of vacuum-heated specimens results in a significant rise in I<sub>2</sub>. Apparently, this is due to the fact that I<sub>2</sub><sup>0</sup> centers localized in the oxide have an energy location different than these very centers localized near the interface (I<sub>2</sub><sup>intf</sup>). Prior to irradiation the I<sub>2</sub><sup>0</sup> centers are neutral and nonparamagnetic. Injection of holes, generated by UV irradiation from Si to SiO<sub>2</sub> [7] moves these centers to a positively charged paramagnetic state. The fact that irradiation results only in recharging of existing states, and not generation of new defects (or photochemical reaction), points to reversibility of the variation in I<sub>2</sub><sup>0</sup> with respect to anneal-reirradiation cycles. As is seen from Fig. 2b, photoactive I<sub>2</sub><sup>0</sup> centers arise in the oxide only after heating under vacuum. This may be associated with dehydration of Si-SiO<sub>2</sub>, for example, according to the scheme:



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